



03-08-02

GP/2823

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Brian A. Vaartstra

Group Art Unit: 2823

Serial No.: 09/865,612

Examiner: D.M. C. **RECEIVED**
MAR 13 2002

Filed: May 25, 2001

Docket No.: 156,080,002
Confirmation No.: 4697
MAIL ROOMTitle: METHODS, COMPLEXES, AND SYSTEMS FOR FORMING METAL-CONTAINING FILMS
ON SEMICONDUCTOR STRUCTURESAssistant Commissioner for Patents
Washington, D.C. 20231

We are transmitting the following documents along with this Transmittal Sheet (which is submitted in triplicate):

- ☒ An itemized return postcard.
☐ A Petition for Extension of Time for __ month(s) and a check in the amount of \$__ for the required fee.
☐ An Information Disclosure Statement (__ pgs); copies of __ applications; 1449 forms (__ pgs); and copies of __ documents cited on the 1449 forms.
☐ A check in the amount of \$__, for __.
☐ A certified copy of a __ application, Serial No. __, filed ____, the right of priority of which is claimed under 35 U.S.C. §119.
☒ Other: Response (4 pgs.)
☐ Amendment __ No Additional fee is required. __ The fee has been calculated as shown:

Fee Calculation for Claims Pending After Amendment					
	Pending Claims after Amendment (1)	Claims Paid for Earlier (2)	Number of Additional Claims (1-2)	Cost per Additional Claim	Additional Fees Required
Total Claims				x \$18 =	
Independent Claims				x \$84 =	
One or More New Multiple Dependent Claims Presented? If Yes, Add \$280 Here →					
Total Additional Claim Fees Required					

Please consider this a PETITION FOR EXTENSION OF TIME for a sufficient number of months to enter these papers and please charge any additional fees or credit overpayment to Deposit Account No. 13-4895. Triplicate copies of this sheet are enclosed.

MUETING, RAASCH & GEBHARDT, P.A.

Customer Number: 26813



26813

PATENT TRADEMARK OFFICE

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CERTIFICATE UNDER 37 CFR §1.10:"Express Mail" mailing label number: EL888272878USDate of Deposit: March 6, 2002

I hereby certify that this paper or fee is being deposited with the United States Postal Service "Express Mail Post Office to Addressee" service under 37 CFR §1.10 on the date indicated above and is addressed to the Assistant Commissioner for Patents, ATTN: Box PATENT APPLICATION, Washington, D.C. 20231.

By: Sue Dombroske
Name: Sue Dombroske

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Docket No. 150.00810102

PATENT

#5/Response
of
3/19/02

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): Brian A. Vaartstra) Group Art Unit: 2823
Serial No.: 09/865,612)
Confirmation No.: 4697) Examiner: D.M. Collins
Filed: May 25, 2001)
For: METHODS, COMPLEXES, AND SYSTEMS FOR FORMING METAL-
CONTAINING FILMS ON SEMICONDUCTOR STRUCTURES

RESPONSE

Assistant Commissioner for Patents
Washington D.C. 20231

Dear Sir:

The Office Action mailed 6 December 2001 has been received and reviewed. Applicant addresses the Office Action as follows.

Remarks

The Office Action mailed December 6, 2001, has been received and reviewed. No claims were amended, cancelled, or added. Claims 18-38 are pending. Reconsideration and withdrawal of the rejections are respectfully requested.

Double Patenting Rejection

Claims 18-38 were rejected under the judicially created doctrine of obviousness-type double patenting as being unpatentable over claims 1-34 of U.S. Patent No. 6,306,217. The Examiner asserted that although the conflicting claims were not identical, they were not patentably distinct from each other because the claims of the instant application show a chemical vapor deposition system. The Examiner asserted that U.S. Pat. No. 6,306,217 shows a chemical vapor deposition system comprising a deposition chamber having a semiconductor substrate and a vessel containing a precursor composition. As such, the Examiner asserted that it would have been obvious to one of ordinary skill in the art at the time the invention was made that using